

## ABSTRACT OF THE DISCLOSURES

In order to supply a scanning charged-particle microscope that can achieve both the improvement of resolution and that of focal depth at the same time, a scanning charged-particle microscope is supplied which is characterized in that a passage aperture for limiting the passage of the charged-particle optical beam is located between the charged-particle source and the scanning deflector, and in that a member for limiting the passage of the charged-particle optical beam is provided at least in the center of the passage aperture.

TO0000-20262-082001